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A detailed technical drawing of a mechanical assembly, possibly a piston or a similar component, rendered in a light gray color. The drawing includes various parts, surfaces, and features, with several numerical callouts (18, 22, 26, 32, 34, 40, 52, 68, 80, 84, 86) indicating specific dimensions or components. The drawing is set against a dark purple background that has a wavy, torn-paper-like edge at the top and bottom.

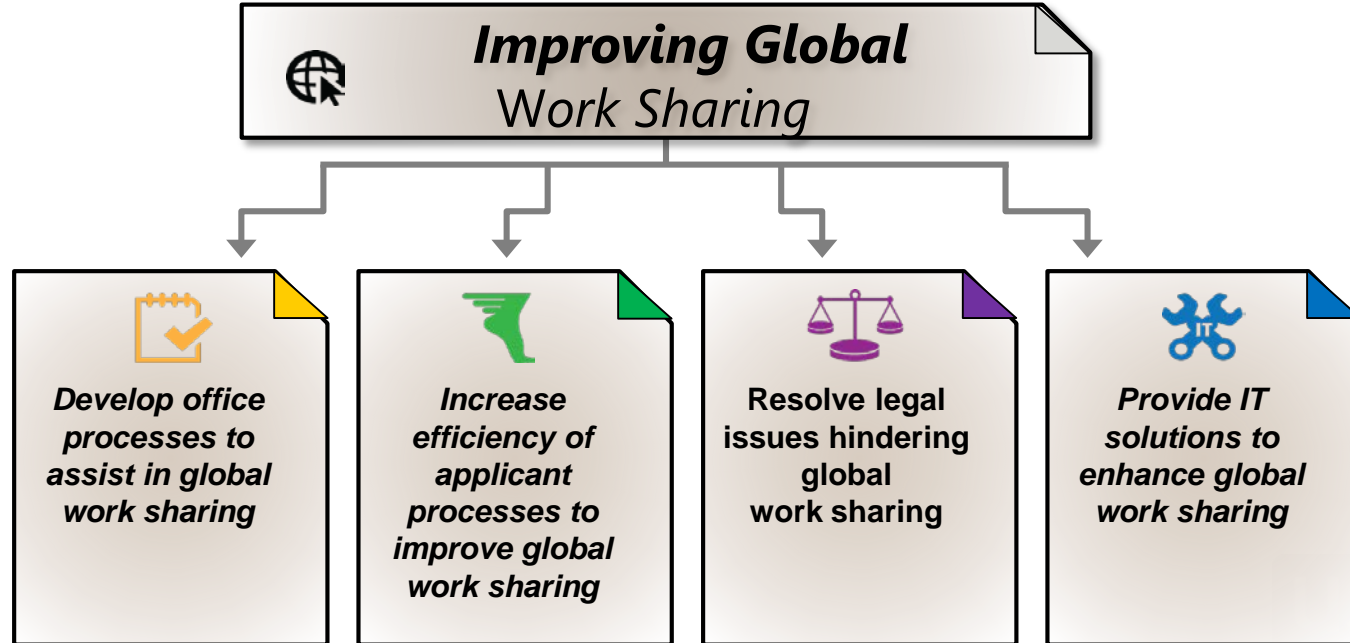
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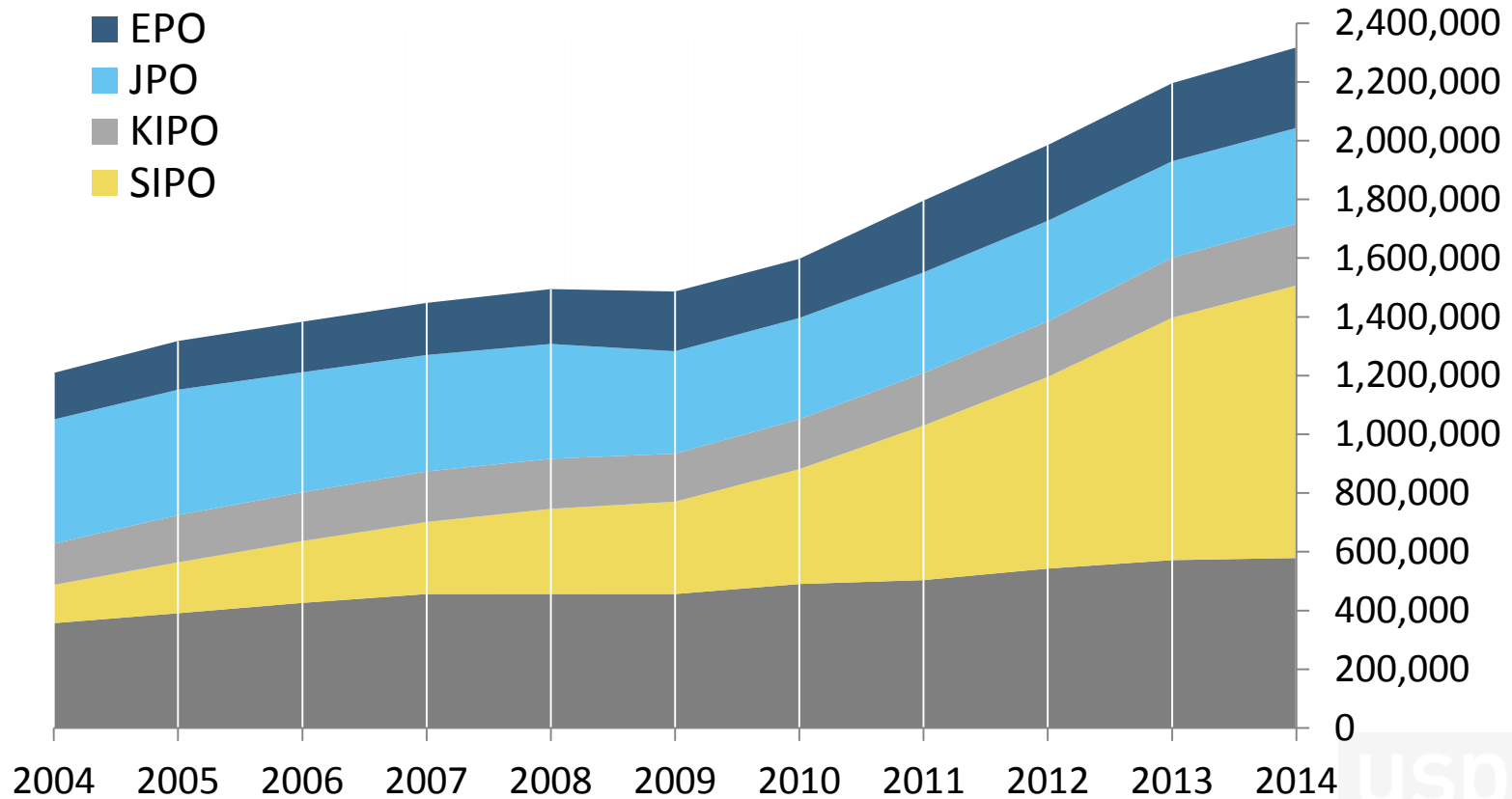
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Evolution of filings at the IP5 (2004-2014)



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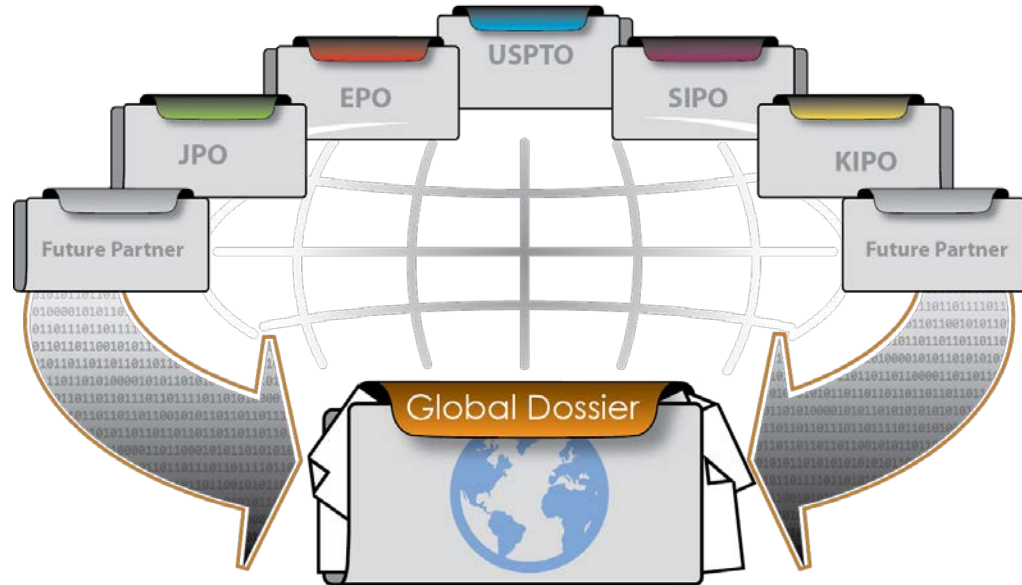
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US 13565455 9 Members in Patent Family (8 currently shown)

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	EP	09811971 View Dossier	1) Applied Materials, Inc.	LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009	US 9204408 US PCT/US09/54677	EP 2329518 A2	06/08/2011	(1) <input type="button" value="Add to ★"/>
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United States Patent Application 20100055901
Kind Code A1
Zhang; Zhenhua ; et al. March 4, 2010

LASER MATERIAL REMOVAL METHODS AND APPARATUS

Abstract

Embodiments of the present invention generally provide methods and apparatus for material removal using lasers in the fabrication of solar cells. In one embodiment, an apparatus is provided that precisely removes portions of a dielectric layer deposited on a solar cell substrate according to a desired pattern and deposits a conductive layer over the patterned dielectric layer. In one embodiment, the apparatus also removes portions of the conductive layer in a desired pattern. In certain embodiments, methods for removing a portion of a material via a laser without damaging the underlying substrate are provided. In one embodiment, the intensity profile of the beam is adjusted so that the difference between the maximum and minimum intensity within a spot focused on a substrate surface is reduced to an optimum range. In one example, the substrate is positioned such that the peak intensity at the center versus the periphery of the substrate is lowered. In one embodiment, the pulse energy is improved to provide thermal stress and physical lift-off of a desired portion of a dielectric layer.

Inventors: Zhang; Zhenhua (Newark, CA); Rana; Virendra V.S. (Los Gatos, CA); Shah; Vinay K. (San Mateo, CA); Eberspacher; Chris. (Palo Alto, CA)
Correspondence Address: PATTERSON & SHERIDAN, LLP - - APPM/TX
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TX
77056
US
Assignee: APPLIED MATERIALS, INC.
Santa Clara
CA

Family ID: 41726084
Appl. No.: 12/545488
Filed: August 21, 2009

Related U.S. Patent Documents

Publication Link

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Office: US Type: Application 13565455 ★ Collections 0 🕒 History 1

US 13565455 9 Members in Patent Family (8 currently shown)

Office	Application	Applicant	Title	App. Date	Priority #	Pub. #	Pub. Date	Action
US	PCT/US09/54677			08/21/2009	US 61092044	WO 2010027712 A2 WO 2010027712 A3	03/11/2010 05/14/2010	
EP	09811971	1) Applied Materials, Inc.	LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009	US 61092044 US PCT/US09/54677	EP 2329518 A2	06/08/2011	(1) Add to ★

DATE DOCUMENT DESCRIPTION OPTIONS

DATE	DOCUMENT DESCRIPTION	OPTIONS
Apr 28, 2015	Claims (ORIGINAL)	⋮
Apr 28, 2015	Argument (TRANSLATED)	⋮
Apr 28, 2015	Argument (ORIGINAL)	⋮

All Documents **Classification and Citation**

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☆ **First Office Action (TRANSLATED)**

The State Intellectual Property Office of People's Republic of China

200233
上海桂平路436号 上海专利商标事务所有限公司
陆嘉

Issuing Date:

Application No. or Publication Issue No.:
No.201310590403.1

Applicant or Patentee APPLIED MATERIALS, INC.

Title of Invention: Laser material removal methods and apparatus

First Office Action

1. Upon the request of substantive examination of the applicant, in accordance with Article 35.1 of the Patent Law, the State Intellectual Property Office performs the substantive examination for the aforesaid application for a patent for invention.

In accordance with Article 35.2 of the Patent Law, the State Intellectual Property Office proceeds to examine the aforesaid application for a patent for invention as to its substance on its own initiative.

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US	PCT/US09/54677	Refresh Dossier		08/21/2009
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US	12545488	1) Zhang, Zhenhua 2) Rana, Virendra V.S. 3) Shah, Vinay K. 4) Eberspacher, Chris	LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009
CN	201310590403	1) APPLIED MATERIALS, INC.		12/2009
CN	200980133793	1) The Applied Materials,	Laser material removal methods and apparatus	08/21/2009

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US	PCT/US09/54677	Refresh Dossier		08/21/2009	US 9204408	WO 2010027712 A2 WO 2010027712 A3	03/11/2010 05/14/2010	
EP	09811971	1) Applied Materials, Inc.	LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009	US 9204408 US PCT/US09/54677			
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Application Number: US 12545488
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Group ID	Title	Date	Code	Options
unknown	Issue Notification	08/15/2012	ISSUENTF	
4	Issue Fee Payment (PTO-85B)	08/01/2012	IFP	
5	Fee Worksheet (S806)	08/01/2012	WFEE	
2	EFS Acknowledgment Receipt	08/01/2012	N417	
102	Search information including classification, databases, and other search related notes	07/06/2012	SPW	
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102	Issue Information including classification, examiner, name, claim, renumbering, etc.	07/06/2012	IPW	
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2	EFS Acknowledgment Receipt	04/27/2012	N417	
4	Response to Election / Restriction Filed	04/27/2012	ELC	
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 HOUSTON, TX 77056

EXAMINER
 TRINOL MICHAEL MANSI

ART UNIT PAPER NUMBER
 3822

DATE MAILED: 07/06/2012

APPLICATION NO.	FILED DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
12545488	08/21/2009	Zhouhai Zhang	013161253SR,AR,CEN,ONG	1445

TITLE OF INVENTION: LASER MATERIAL REMOVAL METHOD AND APPARATUS

APPL. TYPE	SMALL ENTITY	ISSUE FEE DUE	PUBLICATION FEE DUE	PREV. PAID ISSUE FEE	TOTAL FEE(S) DUE	DATE DUE
non-provisional	NO	\$1740	\$300	\$0	\$2040	10/09/2012

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Classification Data

IPC8

H01L 21/027 H01L 31/042

CPC

B23K 26/0853 H01L 31/18 B23K 26/0635 H01L 31/022425
B23K 26/0807 B23K 26/4075 B23K 26/03

No matching citation data found.

B23K 26/0846	{for moving elongated workpieces longitudinally, e.g. wire or strip material}
B23K 26/0853	...	{Devices involving movement of the workpiece in at least in two axial directions, e.g. in a plane}
B23K 26/0861	{in at least in three axial directions}

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Citation Data

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applicant		US20090162972/A1
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applicant		US20090162972/A1
examiner		US20070232009/A1
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applicant		US20020117199/A1
applicant		US20030044559/A1
applicant		US20030129810/A1
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FRIDAY	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59	00:00 - 23:59	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59
SATURDAY	00:00 - 23:00 23:00 - 23:59*	00:00 - 23:59	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59
SUNDAY	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59	00:00 - 23:59	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59

Service Availability Status

Offices

USPTO EPO JPO KIPO SIPO

Check Availability

SERVICE AVAILABILITY STATUS FOR -- USPTO

	Patent Family	Dossier Content	Classification & Citation
Actual	UP	UP	UP
Scheduled	UP	UP	UP

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BROWSE BY TOPIC

- Patents
- Trademarks
- Learning & Resources
- About the USPTO
- Glossary
- Careers
- Contact Us

Upcoming Features

- Enhanced Office Action indicator
- Document filtering
- Enhanced Office availability alerts
- Linkage with WIPO CASE
- PPH pilot

IP5 Priorities for Global Dossier

- USPTO – “Proof-of-Concept for Inter-Office Exchange”
 - Sharing documents between offices including for example, prior art exchanges, bib data updates, and supporting documents. Viewed as a first step towards cross-filing
- EPO – “Alerting”
 - Automated mechanism whereby each office alerts all the other offices, applicants, and representatives of changes in status to an application
- JPO – “XML”
 - Enabling each office, and possibly applicants and representatives, to download all application-related data from applications pending in other offices in XML format
- KIPO – “Applicant Name Standardization”
 - An automated mechanism that will assign a single, unique name to entities with applications pending in multiple office, including in instances where those entities may have used multiple names, or variations of a single name. to identify themselves
- SIPO -- “Legal Status”
 - A mechanism to allow users to view the legal status of an application in another office

Stakeholder Input on Global Dossier

- IdeaScale - <http://uspto-globaldossier.ideascale.com/>
 - IdeaScale is one of the ways that OIPC will be gathering stakeholder input and feedback on Global Dossier.
 - Vote and comment on the various ideas
 - Provide additional suggestions for services and features that would improve the ability to monitor and manage related cases around the world
- Focus Sessions
 - Conducted to gather input and feedback on services
- Contact the Global Dossier Team
 - GlobalDossier@USPTO.gov

Global Dossier Access

Direct access link:
<http://globaldossier.uspto.gov>



Welcome to Global Dossier

Global Dossier Initiative

The Global Dossier Initiative is a set of business services being developed by the IPS Offices (USPTO, EPO, JPO, KIPO, and SIPO) aimed at modernizing the global patent system and delivering benefits to all stakeholders through a single portal/user interface. Global Dossier will provide a single, secure point of access for the management of dossier and examination information, enabling and encouraging streamlining of office procedures among different IP Offices. This will lead to improved efficiency and predictability of global patent family prosecution with increased cost savings provided to patent applicants.

For more information, on the please visit the Global Dossier Initiative page.

Global Dossier Public Access

The first service being provided by the Global Dossier Initiative is a secure, online access to the file histories of related applications from participating IP Offices, which currently include the IPS Offices.

By using this service, users can see the patent family for a specific application, containing all related applications filed at participating IP Offices, along with the dossier, classification, and citation data for these applications. This service also provides Office Action Indicators to help users identify applications that contain office actions, a Collections View for saving documents and applications for review later on in the session, and the ability to download the documents in an application.

Service Hours

Global Dossier users will be able to view the scheduled service hours for each IPS office, including scheduled outages due to holidays and maintenance.

To view the scheduled hours of availability, users can select the **Service Hours** link on the top right corner of the website. In addition, any current scheduled outages for one or more offices will also be displayed on top of the homepage as a reminder for the users.

Users may also verify the availability of application data from each office by selecting the **Current Service Status** link on the top right side of the website.



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A technical drawing of a mechanical assembly, possibly a shaft or a component of a machine, rendered in a light gray color. The drawing includes various parts with hatching and is annotated with numerous numerical callouts such as 18, 80, 22, 26, 68, 40, 36, 34, 32, 52, 84, 86, and 82. The drawing is set against a dark purple background.

Access to Relevant Prior Art

UNITED STATES
PATENT AND TRADEMARK OFFICE



Background

- USPTO is studying how to increase examination efficiency and patent quality through providing examiners with access to relevant prior art and supplemental information at the earliest point in examinations.
- Additionally, exploring whether or not automatically importing relevant prior art into the US application file at the earliest point in examination would improve prosecution efficiency and quality and reduce the burden of duty of disclosure for applicants.

Current Issues: Examiner Perspective

– Examiners

- Awareness/availability: how do examiners know that relevant prior art is available and how do they access it
- Efficiently obtained: how does the relevant prior art get to the examiner in a manner and time that will increase search and examination efficiency and quality
- Value Recognition – what supplemental information is available to assist the examiner in determining the relevance of prior art

Current Issues: Applicant Perspective

– Applicants

- Acquiring Information: how do applicants efficiently obtaining the information necessary to meet their duty of disclosure and assist the examiner in making a proper patentability decision
- Efficiently obtained: how do applicants avoid cumbersome, costly, and time consuming efforts to monitor prosecution in related or counterpart applications or external sources so as to obtain relevant prior art
- Compliant presentation: how do applicants efficiently submit relevant prior art to the examiner in a time and manner such that it complies with relevant regulations

Anticipated Benefits

- Increase in patent quality
- Efficiency of examination is increased
- Examiner access to relevant prior art and supplemental information in a conveniently searchable manner
- Decreased applicant expense of submitting prior art documents and information disclosure statements
- Reduced burden for applicant compliance with duty to disclose information material to patentability

Timeline

- Stage 1: Three track parallel information gathering
 - Track 1 – IT & Data Source Gathering
 - Track 2 – Application Studies Data Gathering
 - Track 3 – Data gathering from internal and external stakeholders
- Stage 2: Information Review
- Stage 2.5: Business Solution Development
- Stage 3: IT Development and Implementation

Thank you!

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